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TC 1700



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

KAZUNORI ITO ET AL

: EXAMINER: MCDONALD, R.

SERIAL NO: 09/498,375

:

FILED: FEBRUARY 4, 2000

: GROUP ART UNIT: 1753

FOR: OPTICAL DEVICE SUBSTRATE
FILM-FORMATION
APPARATUS, OPTICAL DISK
SUBSTRATE FILM-FORMATION
METHOD, SUBSTRATE HOLDER
MANUFACTURE METHOD,
SUBSTRATE HOLDER, OPTICAL
DISK AND A PHASE-CHANGE
RECORDING TYPE OF OPTICAL
DISK

8/A
W.M.
11/1/02

AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231

SIR:

In response to the Official Action mailed July 31, 2002, please amend this application as follows:

IN THE SPECIFICATION

Page 10, beginning at line 12, please replace the paragraph as follows: /

A
It is another object of the present invention to make it possible to take out and carry a substrate with a film having been formed by sputtering efficiently at a high speed in an apparatus used for forming a film by closely contacting at least one portion of a rear surface